

Paragraph at page 16, line 2 to page 16, line 11:

It is assumed that, in FIG. 5 which shows a configuration of a semiconductor device inspection apparatus of a preferred embodiment of the present invention, tester 11 is used to inspect two semiconductor devices 14a, 14b simultaneously, for the convenience of description. Each of semiconductor devices 14a, 14b includes three inputting terminals 15a to 15c, 15d to 15f. Tester 11 includes a plurality of drivers 12a, 12b, 12c, 12d, . . . , and signals from the drivers are applied to semiconductor devices 14a, 14b through probe card 13.

In the Claims:

Please amend claims pursuant to 37 CFR 1.121(c)(1)(i) as set forth in the "clean" version below. Entry is respectfully requested. A version with markings to show the changes made pursuant to 37 CFR 1.121(c)(1)(ii) is attached hereto as Appendix A.

Claim 1. (Amended) An inspection method for simultaneously inspecting a plurality of semiconductor devices each having a respective input terminal for receiving an input signal, the method comprising:

preparing a driver for outputting a signal to be used for inspection;

connecting an output terminal of said driver to a branching point;

connecting the respective input terminals of the semiconductor devices and the branching point through a current limiting element and a capacitor, said capacitor being connected in parallel to said current limiting element; and

outputting said signal from said driver toward said branching point.

Claim 7. (Amended) An inspection method for simultaneously inspecting a plurality of semiconductor devices each having a first terminal and a second terminal for receiving an input signal, the method comprising:

preparing a first driver for outputting a first signal to be used for inspection;

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A preparing a plurality of second drivers for outputting a second signal to be used for inspection;

connecting an output terminal of said first driver to a branching point;

connecting each of the first terminals of the semiconductor devices and the branching point through a current limiting element and a capacitor, said capacitor being connected in parallel to said current limiting element;

connecting output terminals of said plurality of second drivers and the second terminals to each other; and

outputting said first signal from said first driver toward said branching point and outputting said second signal from said plurality of second drivers to said second terminals.

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X Claim 14. (Amended) An inspection apparatus for simultaneously inspecting a plurality of semiconductor devices each having a respective input terminal for receiving an input signal, the inspection apparatus comprising:

a driver for outputting a signal to be used for inspection;

a branching point to which an output terminal of said driver is connected;

a current limiting element interposed between each of the respective input terminals of the semiconductor devices and said branching point; and

Amend'd
a capacitor connected in parallel to each of the current limiting elements.

Claim 21. (Amended) An inspection apparatus for simultaneously inspecting a plurality of semiconductor devices each having a first terminal and a second terminal for receiving an input signal, the inspection apparatus comprising of:

a first driver for outputting a first signal to be used for inspection;

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a plurality of a second drivers for outputting a second signal to be used for inspection;

a branching point to which an output terminal of said first driver is connected;

a current limiting element interposed between the first terminals of the semiconductor devices and said branching point; and

a capacitor connected in parallel to said current limiting element;

wherein output terminals of said plurality of second drivers and the second terminals are connected to each other.